

PATENT 0941-0754P

## IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: LEE, Brian S. et al. Conf.: 7276

Appl. No.:

10/600,466

Group: 2811

Filed:

June 23, 2003

Examiner: D. W. Owens

For:

SEMICONDUCTOR DEVICE WITH LOOP LINE STRUCTURE METHOD AND ALTERNATING PHASE SHIFT MASK

FOR FABRICATING THE SAME

## LARGE ENTITY TRANSMITTAL FORM

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 May 24, 2004

## Sir:

Transmitted herewith is a Reply to Restriction/Election

Requirement in the above-identified application.	
	The enclosed document is being transmitted via the Certificate of Mailing provisions of 37 C.F.R. § 1.8.
	Petition for ( ) month(s) extension of time pursuant to 37 C.F.R. §\$ 1.17 and 1.136(a). \$0.00 for the extension of time.
$\boxtimes$	No fee is required.
	A check in the amount of \$0.00 is enclosed.
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Respectfully submitted,

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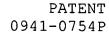
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0941-0754P

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Attachment(s)

(Rev. 02/08/2004)





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Applicant: LEE, Brian S. et al. Conf.: 7276

Appl. No.: 10/600,466 Group: 2811

Filed: June 23, 2003 Examiner: Douglas W. Owens

For: SEMICONDUCTOR DEVICE WITH LOOP LINE PATTERN

STRUCTURE METHOD AND ALTERNATING PHASE SHIFT MASK

FOR FABRICATING THE SAME

# REPLY TO RESTRICTION REQUIREMENT

Assistant Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

May 24, 2004

Sir:

Responsive to the Office Action dated May 6, 2004, the following election and remarks are respectfully submitted in connection with the above-identified application.

#### REMARKS

Claims 1-10 are now pending in the present application.

The Examiner has given the following Restriction Requirement:

Group I, claims 1-4, 7 and 8, drawn to a semiconductor device;

Group II, claims 9 and 10, drawn to a method of making a semiconductor device; and

Group III, claims 5 and 6, drawn to a phase-shift mask.

In response to this requirement, Applicants hereby elect Group 2, claims 9 and 10, drawn to a method of making a semiconductor device. This election is with traverse.

It is respectfully submitted that it should be no undue burden on the Examiner to consider all claims in the single application.